

Special Issue

Computational Imaging for Semiconductor Devices Metrology Applications

Message from the Guest Editor

For decades, the fabrication of semiconductor devices has been driven by Moore's law and has been powered by advancements in photolithography. The ecosystem of a modern semiconductor devices foundry includes metrology tools for every step of the fabrication process, from the control of the photomask and the EUV pellicle, to the characterization of every layer of the printed wafer. This special issue aims to investigate the opportunities and the possibilities offered by computational imaging in addressing the raising challenges in the metrology required by the semiconductor industry. Topics of interest include, but are not limited to:

- Computational imaging techniques for EUV photomask and pellicle inspection
- High-resolution lensless imaging for semiconductor wafers
- New algorithms and methods for improving metrology accuracy
- Applications of machine learning in semiconductor metrology
- Cost-effective metrology tools for scaling semiconductor devices
- Novel approaches to overcoming challenges in high-resolution semiconductor imaging

Guest Editor

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